

FEB 28 2003

PATENT & TRADEMARK OFFICE

00802.0022167

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#8
3/7/03
JFE

In re Application of:

Shinichi HARA et al.

Application No.: 09/818,625

Filed: March 28, 2001

For: EXPOSURE APPARATUS, GAS REPLACEMENT
METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, SEMICONDUCTOR
FACTORY, AND EXPOSURE APPARATUS
MAINTENANCE METHOD

Examiner: D. Ben Esplin
Group Art Unit: 2851

February 28, 2003

Commissioner for Patents
Washington, D.C. 20231

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TECHNOLOGY CENTER 2800

REQUEST FOR APPROVAL OF DRAWING CHANGES

Sir:

Applicants request that the Examiner approve the changes to Figures 3 and 13, as shown in red on the attached sketches, enclosed in duplicate.

In Figure 3, the topmost reference numeral "111" should read -- 113 --, as shown.

In Figure 13, in step S13, "FORM" should read -- FORM --, as shown.

Favorable consideration is requested.

Accepted
DBE 3/19/03

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010 All correspondence should continue to be directed to our address given below.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "Steven E. Warner", is written over a horizontal line.

Attorney for Applicant
Steven E. Warner
Registration No. 33,326

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